

INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)	Docket Number (Optional) SHIG CFP03US013	Application Number 10/559921
	Applicant(s) JU	
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U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
WB		6,879,167	4/12/05	JU ET AL.	G01R	27/04	

U.S. PATENT APPLICATION PUBLICATIONS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
WB		61-173171	04.08.1986	JAPAN (w/abstract)	G01R	27/02		✓
WB		09-021837	21.01.1997	JAPAN (w/abstract)	G01R	27/02		✓
WB		2004-177274	24.06.2004	JAPAN (w/abstract)	G01R	27/02		✓

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

WB		"Contactless measurement of electrical conductivity of semiconductor wafers using the reflection of millimeter waves", Ju et al., Journal of Applied Physics Letters, Vol. 81n19, 2002, pp. 3585-3587.

EXAMINER /Walter Benson/	DATE CONSIDERED 05/23/2006
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.